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CONTENTS

1. Introduction to Scanning Electron Microscopy	1
1.1 The background	1
1.2 The scanning electron microscope	4
1.3 The logic of scanning electron microscopy	8
2. The Interaction of Electrons with Solids	24
2.1 Introduction	24
2.2 Electron range	25
2.3 Secondary electron emission	29
2.4 Specimen currents and voltages induced by the primary electron beam	39
2.5 Cathodoluminescence	40
2.6 X-ray emission	42
2.7 Auger electron emission	44
2.8 Summary and conclusions	46
3. The Design and Use of the Scanning Electron Microscope	49
3.1 Introduction	49
3.2 The formation of an electron beam	50
3.3 Resolution and contrast in the scanning electron microscope	53
3.4 The basic facilities required in an operating microscope	65
3.5 Main features of commercially available microscopes	68
3.6 Conclusion	74
4. Specimen Preparation	75
4.1 Introduction	75
4.2 Specimen coating	76
4.3 Low beam energy work	83
4.4 Replication	85
4.5 Conclusion	85
5. Procedures for Using a Scanning Electron Microscope	87
5.1 Introduction	87
5.2 Use procedure of the emissive mode	90
5.3 Use procedure of the reflective mode	98
5.4 Cathodoluminescent mode	99
5.5 X-ray spectroscopy	99
5.6 Specimen current mode	101
5.7 The mirror mode	101
5.8 The transmission mode	101
5.9 Conclusions	102

6. Applications to Metallurgy	104
6.1 Introduction	104
6.2 Fractography in the study of failure mechanisms	109
6.3 Physical structure of metals, alloys and composite materials	117
6.4 Studies of surface morphology	124
6.5 Chemical metallurgy	129
6.6 Conclusions	135
7. Applications to Fibres and Polymers	139
7.1 Introduction	139
7.2 Operating conditions for polymers and fibres	141
7.3 Coating materials	141
7.4 Textile fibres	142
7.5 Textile yarns and fabrics	153
7.6 Bulk polymers	157
7.7 Dynamic and special experiments	158
7.8 Conclusions	162
8. Applications to Solid-state Electronics	164
8.1 Introduction	164
8.2 Investigation of materials	165
8.3 Investigation of semiconductor devices	169
9. Applications to Biological Materials	177
9.1 Introduction	177
9.2 Modes of examination	177
9.3 Ancillary techniques	184
9.4 Preparation of labile biological material	192
10. Faults	203
10.1 Introduction	203
10.2 Faults, which result in no image on the display, tube	203
10.3 Faults which result in an obvious distorted image or image of low quality	205
10.4 Faults which may not be obvious on the final photomicrograph	216
11. Dimensional Measurements	219
11.1 Introduction	219
11.2 Three-dimensional viewing	219
11.3 Simple quantitative measurement techniques	222
11.4 Rigorous treatment	226
11.5 The use of stereographic equations	230
11.6 Extension of the basic theory to the low magnification case	233
11.7 Further applications of stereographic techniques	234
11.8 Miscellaneous measurement techniques	235
12. Management of the SEM	239

12.1 Introduction	239
12.2 Organization	239
12.3 Location and facilities	240
12.4 Operation	243
12.5 Maintenance	248
12.6 Rental service	249
12.7 Photography	249
12.8 Visitors	250
12.9 Conclusion	250
13. The Future of Scanning Electron Microscopy	251
13.1 The pattern of development	251
13.2 Instrument developments	253
13.3 Techniques	255
13.4 Signal processing	259
13.5 Conclusions	262
LIST OF MANUFACTURERS AND SUPPLIERS	266
AUTHOR INDEX	269
SUBJECT INDEX	273